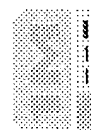


IEEE HOME | SEARCH IEEE | SHOP | WEB ACCOUNT | CONTACT IEEE


[Membership](#) [Publications/Services](#) [Standards](#) [Conferences](#) [Careers/Jobs](#)



 Welcome  
 United States Patent and Trademark Office


» Search

[Help](#) [FAQ](#) [Terms](#) [IEEE Peer Review](#)

Quick Links

## Welcome to IEEE Xplore

- ☐ Home
- ☐ What Can I Access?
- ☐ Log-out

## Tables of Contents

- ☐ Journals & Magazines
- ☐ Conference Proceedings
- ☐ Standards

## Search

- ☐ By Author
- ☐ Basic
- ☐ Advanced

## Member Services

- ☐ Join IEEE
- ☐ Establish IEEE Web Account
- ☐ Access the IEEE Member Digital Library

Print Format

 Your search matched **10** of **1046194** documents.

 A maximum of **500** results are displayed, **15** to a page, sorted by **Relevance Descending** order.

## Refine This Search:

You may refine your search by editing the current search expression or enter a new one in the text box.

sem &lt;and&gt; cad

Search

☐ Check to search within this result set

## Results Key:

**JNL** = Journal or Magazine   **CNF** = Conference   **STD** = Standard

**1 An automated system for LSI fine pattern inspection based on comparison of SEM images and CAD data**

Ito, M.;

 Robotics and Automation, 1995. Proceedings., 1995 IEEE International Conference on , Volume: 1 , 21-27 May 1995  
 Pages:544 - 549 vol.1
[\[Abstract\]](#)[\[PDF Full-Text \(504 KB\)\]](#)

IEEE CNF

**2 CAD driven high precision E-beam positioning**

Kwang, K.; Wang, H.; Hu, A.; Asaki, M.; Nijima, H.;

 Test Conference, 1993. Proceedings., International , 17-21 Oct. 1993  
 Pages:928 - 935
[\[Abstract\]](#)[\[PDF Full-Text \(476 KB\)\]](#)

IEEE CNF

**3 FINDER: A CAD System-Based Electron Beam Tester for Fault Diagnosis of VLSI Circuits**

Kuji, N.; Tamama, T.; Nagatani, M.;

 Computer-Aided Design of Integrated Circuits and Systems, IEEE Transactions on , Volume: 5 , Issue: 2 , April 1986  
 Pages:313 - 319
[\[Abstract\]](#)[\[PDF Full-Text \(1008 KB\)\]](#)

IEEE JNL

**4 Three-dimensional wound surface area calculations with a CAD surface element model**

Tuch, D.S.; Lee, R.C.;

Biomedical Engineering, IEEE Transactions on , Volume: 45 , Issue: 11 , Nov.

Pages:1397 - 1400

[\[Abstract\]](#) [\[PDF Full-Text \(160 KB\)\]](#) IEEE JNL

---

**5 Conductive adhesives for high-frequency applications**

*Sihlbom, R.; Dernevik, M.; Lai, Z.; Starski, P.; Liu, J.;*

The First IEEE International Symposium on Polymeric Electronics Packaging , Oct. 1997

Pages:123 - 130

[\[Abstract\]](#) [\[PDF Full-Text \(624 KB\)\]](#) IEEE CNF

---

**6 Identification and removal of defects on silicon wafer processed with rinse with/without megasonics in DI water**

*Heui-Gyun Ahn; Sang-Young Kim; Jeong-Gun Lee;*

VLSI and CAD, 1999. ICVC '99. 6th International Conference on , 26-27 Oct.

Pages:459 - 462

[\[Abstract\]](#) [\[PDF Full-Text \(244 KB\)\]](#) IEEE CNF

---

**7 Utilizing an integrated yield management system to improve the return on investment in IC manufacturing**

*Castrucci, P.; Dickerson, G.; Bakker, D.;*

Semiconductor Manufacturing Science Symposium, 1991. ISMSS 1991., IEEE, International , 20-22 May 1991

Pages:25 - 29

[\[Abstract\]](#) [\[PDF Full-Text \(492 KB\)\]](#) IEEE CNF

---

**8 Conductive adhesives for high-frequency applications**

*Sihlbom, R.; Dernevik, M.; Lai, Z.; Starski, J.P.; Liu, J.;*

Components, Packaging, and Manufacturing Technology, Part A, IEEE Transactions on [see also Components, Hybrids, and Manufacturing Technology, IEEE Transactions on] , Volume: 21 , Issue: 3 , Sept. 1998

Pages:469 - 477

[\[Abstract\]](#) [\[PDF Full-Text \(312 KB\)\]](#) IEEE JNL

---

**9 Digital processing of VLSI circuit images obtained from a scanning electron microscope**

*Zolghadrasli, A.;*

Circuits and Systems, IEEE Transactions on , Volume: 37 , Issue: 6 , June 19

Pages:824 - 827

[\[Abstract\]](#) [\[PDF Full-Text \(296 KB\)\]](#) IEEE JNL

---

**10 Electrically conductive adhesives at microwave frequencies**

*Dernevik, M.; Sihlbom, R.; Axelsson, K.; Zonghe Lai; Johan Liu; Starski, P.;*

Electronic Components and Technology Conference, 1998. 48th IEEE , 25-28 1998

Pages:1026 - 1030

[\[Abstract\]](#) [\[PDF Full-Text \(552 KB\)\]](#) IEEE CNF

---

[Home](#) | [Log-out](#) | [Journals](#) | [Conference Proceedings](#) | [Standards](#) | [Search by Author](#) | [Basic Search](#) | [Advanced Search](#) | [Join IEEE](#) | [Web Account](#) | [New this week](#) | [OPAC Linking Information](#) | [Your Feedback](#) | [Technical Support](#) | [Email Alerting](#) | [No Robots Please](#) | [Release Notes](#) | [IEEE Online Publications](#) | [Help](#) | [FAQ](#) | [Terms](#) | [Back to Top](#)

Copyright © 2004 IEEE — All rights reserved